

NANOSCALE 2023 AT A GLANCE



Venue: [Technopolis Ruoholahti](#), Address: [Hiilikatu 3, 00180 Helsinki, Finland](#)

Version 1.3 of 2023-09-19 (page numbers added)

Finnish time is East European Summer Time (eest)! This list is intended as a quick&easy overview only. For the details incl. all co-authors, their affiliations, exact times of all talks, coffee-breaks and other information, please see the detailed Session Programme and List of Posters in the Book of Abstracts (page numbers as reference).

Tuesday, 11:00-13:00	CHECK-IN	3
	Handout of Book of Abstracts and name badges. Poster boards ready for the posters, please place your poster there. <i>Please note: No lunch served at NanoScale on Tuesday. We recommend to have an early lunch in town or on your way to NanoScale; there is also a restaurant on the Technopolis Ruoholahti campus, next door to the building where NanoScale takes place. Delegates of TC-L and consortium members of TracOptic will have an early lunch in Espoo directly after the closure of their meetings and will then be brought to NanoScale by shuttle bus. Information will be given at the TC-L/TracOptic meetings.</i>	
Tuesday, 13:00-13:15	OPENING & WELCOME	
M. Heinonen Virpi, Thorsten	Welcome by the Vice-President of VTT MIKES Opening Remarks	
Tuesday, 13:15-14:35	1st Session – Crystalline calibration standards – chaired by Alexandra Delvallée	13
A-1 I. Busch	New ways to calibrate microscopes at nanoscale: How the Silicon lattice parameter is used for new type calibration artefacts	13
A-2 M. A. Lawn	Step height measurement of monoatomic silicon crystal lattice steps with a commercial Atomic Force Microscope	15
A-3 L. Daul	New UHV facility for series production of low-cost crystalline standards	17
A-4 Yushu Shi	Evaluation of the influence of magnification variation on the silicon lattice spacing measurement in high-resolution TEM	19
Tuesday, 15:00-16:40	POSTER SESSION A – please see list of posters at the end of this “NanoScale 2023 at a glance”	
Tuesday, 16:40-18:00	2nd Session – MetExSPM Session I – chaired by Antti Lassila	25
B-1 V. Korpelainen	MetExSPM (EMPIR-project 20IND08): Development of traceable methods for high speed and large range SPM	25
B-2 T. Gotszalk	Application of active piezoresistive cantilevers in high-eigenmode surface imaging	27
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B-4 P. Klapetek	Data processing in metrological high-speed Scanning Probe Microscopes	31
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C-4	A. Mattila Artificial Neural Network-Assisted Spectral Scatterometry for Grating Quality Control	39
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D-5	M. Zucco Selection of appropriate instrumentation and procedures for data evaluation and uncertainty estimation (WP 4)	53
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Thursday, 12:00-13:00	LUNCH (included for all NanoScale participants)	
Thursday, 13:00-17:00	LAB TOURS AT VTT MIKES IN ESPOO – please have ID card/passport ready and allow ample time for the lab visits! Transfer from NanoScale directly to VTT MIKES by chartered shuttle bus. Return in the evening on individual basis, e. g. by Metro.	

POSTERS

Please keep your posters on the posterboards throughout the conference so that they can be visited also in all coffee breaks. **109**

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